

Express Mail No.EV331755906US Attorney Docket No. UMC-96-279 CON Client/Matter No. 81848.0016.001

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Chih-Chien Liu, Ta-Shan Tseng, W. B. Shieh, J. Y. Wu, Water Lur and Shih-Wei Sun

Serial No. 09/546,174

Filed: April 11, 2000

For: HIGH DENSITY PLASMA CHEMICAL

VAPOR DEPOSITION PROCESS

25/04

Group Art Unit: 1711

Examiner: Sergent, Rabon A.

Confirmation No.: 4793

UNDER 37 C.F.R. 1.97

MAIL STOP PETITIONS Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Sir:

Applicant hereby submits for filing under 37 CFR 1.97 a disclosure statement. In submitting this reference, no representation is made or implied that the reference is or is not material to the examination of this application. The patents, publications or other information of which Applicant is presently aware are listed in Form PTO/SB/08A submitted herewith and a copy of such patent and English translation is attached hereto.

No fee is believed due for this submittal. However, any fee deficiency associated with this submittal may be charged to Deposit Account No. 50-1123.

Respectfully submitted,

Date

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Sheet	1	of	1	Attorney Docket No.	UMC-96-279 CON
(Use as many sheets as necessary)				Examiner Name	Sergent, Rabon A.
INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Art Unit	1711
				First Named Inventor	Chih-Chien Liu et al.
				Filing Date	April 11, 2000
Substitute for form	\$449A/PTO			Application Number	09/546,174

			U.S. PATENT	DOCUMENTS		
Examiner Cite Initials No.1		Document No. No. – Kind Code ²	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Doc	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	
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			FOREI	GN PATENT DOCUM	ENTS	
Examiner Cite		Foreign Patent Document Country Code ³ Number ⁴ Kind Code ⁵	Publication Da MM-DD-YYY			T ⁶
		JP-A 7-92839	11/01/1996	Sony Corporation		Yes
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EXAMINER	DATE
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